Special Issue

Corrosion and Etching at Micro/Nanoscale

Message from the Guest Editors

I am very glad to invite you to contribute to this Special Issue of *Micromachines*. Corrosion and etching at micro (nano) scale is an important topic in several fields, from the fabrication of sensors and membranes to investigations of the properties of micro- and nano-composites. The study of this phenomena is essential to acquire knowledge on the physical and mechanical properties of synthesized materials and their resistance to corrosion. This Special Issue is devoted to the review and discussion of all theoretical and practical aspects of these processes. Both experimental and theoretically based contributions related to fabrication via etching processes and the characterization of corrosion resistance in microdevices and composites are welcome.

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